



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450
www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
-----------------	-------------	----------------------	---------------------	------------------

10/033,114

10/22/2001

Tai-Peng Lee

M-11912 US

7687

32605

7590

04/06/2005

MACPHERSON KWOK CHEN & HEID LLP
1762 TECHNOLOGY DRIVE, SUITE 226
SAN JOSE, CA 95110

EXAMINER

GARCIA, JOANNIE A

ART UNIT

PAPER NUMBER

2823

DATE MAILED: 04/06/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1-5, 8-10, 12-16, 19, 20, 23-25, 28-30, 33-36, 39-41, 45, and 53-55, are rejected under 35 U.S.C. 102(e) as being anticipated by Vassiliev et al (U.S. Patent 6,583,069).

Vassiliev et al discloses depositing silicon dioxide into trenches defined in a semiconductor substrate over an electrically metal layer used as an interconnect, where at least two of the trenches are of different aspect ratio (Abstract, and Figure 4B), said depositing method comprising using oxygen and silane gases to reactively form, deposit, and resputter silicon dioxide in substrate 101 by a HDP-CVD process for deposition into at least two trenches of different aspect ratios and widths, wherein a first trench is at least twice as wide a second of the trenches (Figure 4B, Column 1, lines 37-52, and Column 2, lines 21-34, and 53-57), using ions to sputter etch a portion of the formed silicon dioxide during the deposition so as to fill the trenches with the formed silicon dioxide without creating voids of substantial size during said filling of said trenches, wherein the ions include helium (Figure 4B, and Table 1), controlling the etch and deposition of the silicon dioxide such that a nonzero etch to deposition ratio of about 0.07 or less, such as a range between 0.03 to 0.3, is established during the filling of said different trenches (Table 1), using an oxygen to silane ratio of 1.3 or less (Abstract), using a total gas flow of the oxygen, the silane, and an inert gas of 625 sccm, 500 sccm, or less (Table 1), and doping the silicon dioxide during deposition (Column 1, lines 15-35).

Claims 6, 7, 17, 18, 21, 22, 26, 27, 31, 32, 37, 38, and 42, are rejected under 35 U.S.C. 103(a) as being unpatentable over Vassiliev et al as applied to claims 1-5, 8-10, 12-16, 19, 20, 23-25, 28-30, 33-36, 39-41, 45, and 53-55, above, and further in view of the following comments.

Vassiliev et al discloses the claimed invention except using a high frequency bias signal power of 2000 Watts, 1500 Watts, or less, a width of a first trench of said trenches is in the range of 1800 to 3300 Angstroms, and a width of a second of said trenches is in the range of 6600 to 8800 Angstroms. It would have been obvious to one having ordinary skill in the art at the time the invention was made to determine a suitable power, and widths, since it has been held that where the general conditions of a claim are disclosed in the prior art, discovering the optimum or workable ranges involves only routine skill in the art. *In re Aller*, 105 USPQ 233.

In addition, the selection of a suitable power, and widths, is obvious because it is a matter of determining optimum process conditions by routine experimentation with a limited number of species of result effective variables. These claims are prima facie obvious without showing that the claimed ranges achieve unexpected results relative to the prior art range. *In re Woodruff*, 16 USPQ2d 1935, 1937 (Fed. Cir. 1990). See also *In re Huang*, 40 USPQ2d 1685, 1688 (Fed. Cir. 1996)(claimed ranges or a result effective variable, which do not overlap the prior art ranges, are unpatentable unless they produce a new and unexpected result which is different in kind and not merely in degree from the results of the prior art). See also *In re Boesch*, 205 USPQ 215 (CCPA) (discovery of optimum value of result effective variable in known process is ordinarily within skill or art) and *In re Aller*, 105 USPQ 233 (CCPA 1995) (selection of optimum ranges

within prior art general conditions is obvious).

Note that the specification contains no disclosure of either the critical nature of the claimed power, and widths, or any unexpected results arising therefrom. Where patentability is said to be based upon particular chosen powers, and widths, or upon another variable recited in a claim, the Applicant must show that the chosen powers, and widths, are critical. *In re Woodruf*, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

Claims 43, 44, 46-52, and 56-58, are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

Claim 11, is allowed.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Joannie Garcia whose telephone number is (571) 272-1861. The examiner can normally be reached on Monday through Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri, can be reached on (571) 272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Art Unit: 2823


Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).



JAG

March 31, 2005

GFourson
Primary Examiner



George Fourson
Primary Examiner
Art Unit 2823